

TEM and SEM characterization of Pd₂Si nanorods

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INTRODUCTION

Palladium silicide is an interesting material for the use in electronic applications due to its mechanical properties and good electrical conductivity. This resulted that Pd₂Si was applied as a material in contact ohm, Schottky diodes or hydrogen sensors. In this paper we presents bottom to top grow the Pd₂Si nanorods obtained in the PVD/CVD process.

EXPERIMENTAL PART

Pd₂Si nanorods (NR) grown from palladium carbon films deposited on the silicon substrate. This films were prepared in two steps process with the use of physical vapor deposition (PVD) and chemical vapor deposition (CVD). In the first step, fullerenes C₆₀ and palladium acetate were deposited on silicon substrate in PVD process. In the second step, the obtained film was modified in CVD process at temperature of 750°C for 30 minutes in the presence of xylene.

RESULTS

Palladium silicide was investigated with the usage of SEM, XRD and TEM methods. SEM image of a Pd-C film and hedgehogs-like structures are shown in Fig.1. We prepared cross section of the structure used a focused ion beam (FIB). In the Fig.2 is presented the hedgehog - like structure. It is visible that NR's grow is chaotically. Distribution of elements with the usage Energy Filtering TEM measurement is presented in Fig.3. The XRD analysis showed occurrence Pd₂Si (Fig. 4), which was also confirmed by electron diffraction from the single Pd₂Si rod (Fig.5).

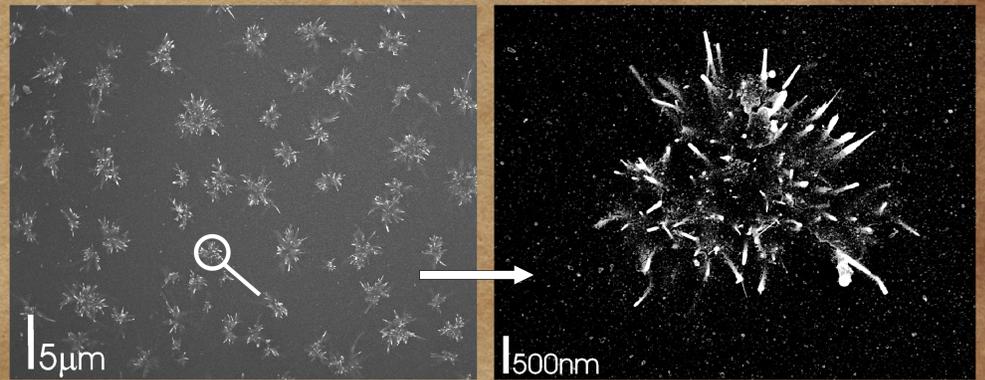


Fig.1. SEM image of a Pd-C film and hedgehogs - like structures.

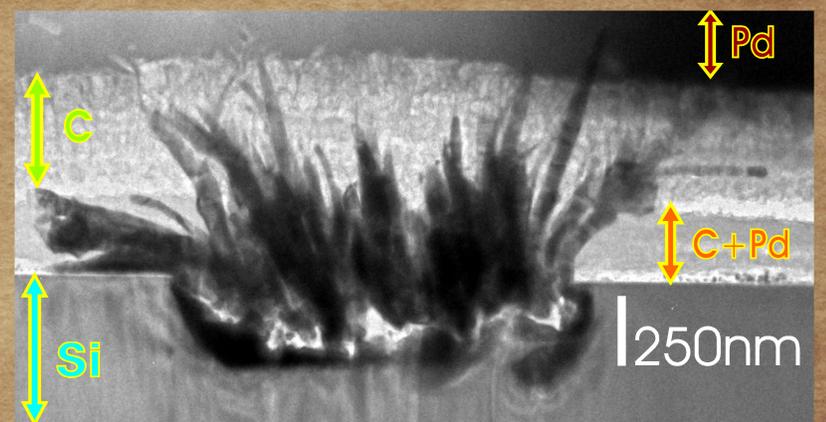


Fig.2. TEM image of lamella of the hedgehog-like structure.

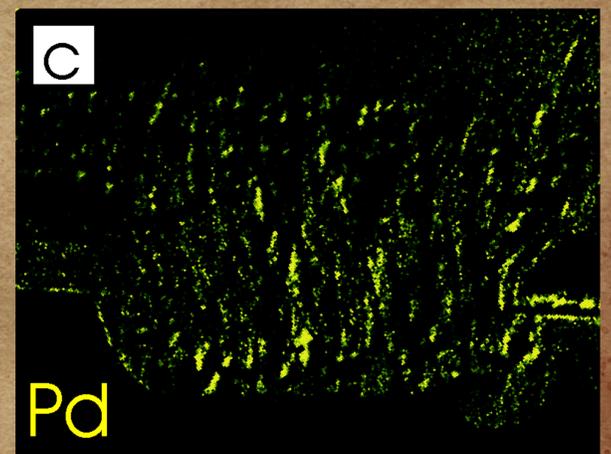
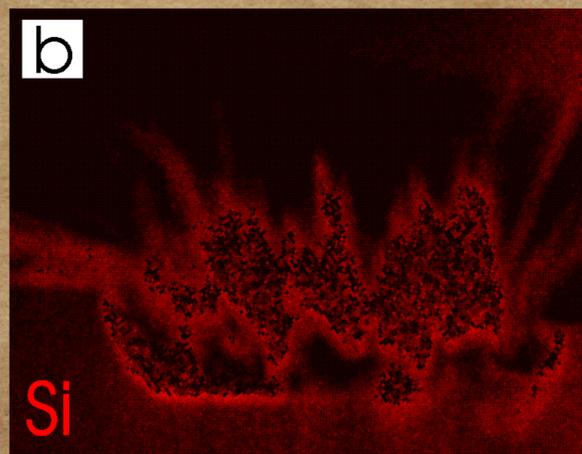
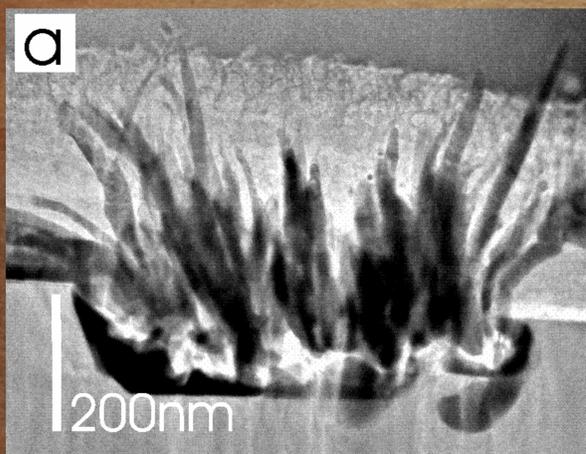


Fig.3. a) TEM image b) Si map c) Pd map.

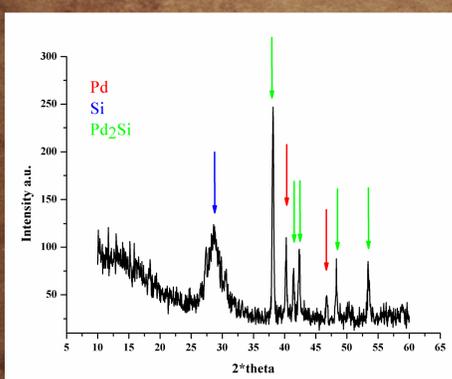


Fig.4. XRD spectrum from Pd-C film

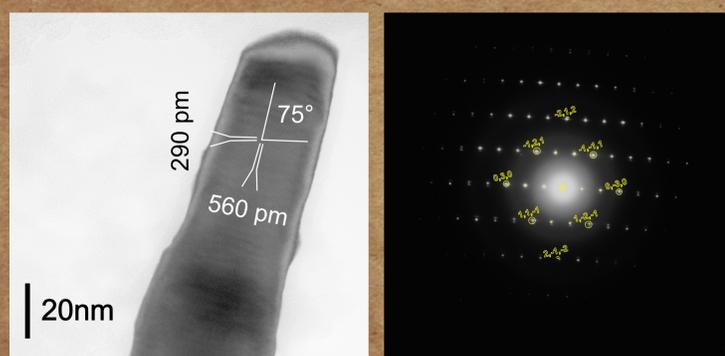


Fig.5. TEM image of a single rod with electronogram

CONCLUSION

The growth of palladium silicide is possible when two requirements are fulfilled – the temperature and the concentration of palladium crystallites. One of them is the agglomeration of palladium which is observed in the sample obtained in the PVD process. The second, is temperature – higher than 650°C, fulfilled in the CVD process.

